

In the Abstract

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ABSTRACT OF THE DISCLOSURE

An electrically-coupled micro-electro-mechanical system (MEMS) filter system and method are disclosed. In one embodiment, the MEMS filter system comprises a first MEMS resonator, and a second MEMS resonator closely spaced and mechanically separate from the first MEMS resonator, wherein the second MEMS resonator is electrically coupled to the first MEMS resonator.